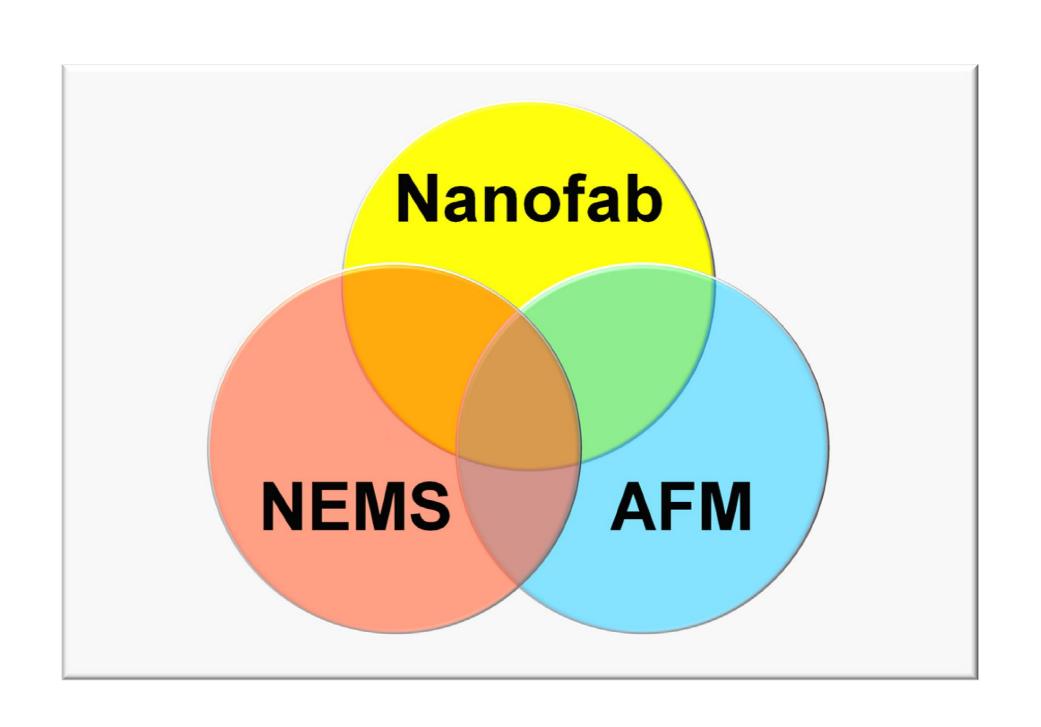
NEMS and Nanofabrication



SCOPE

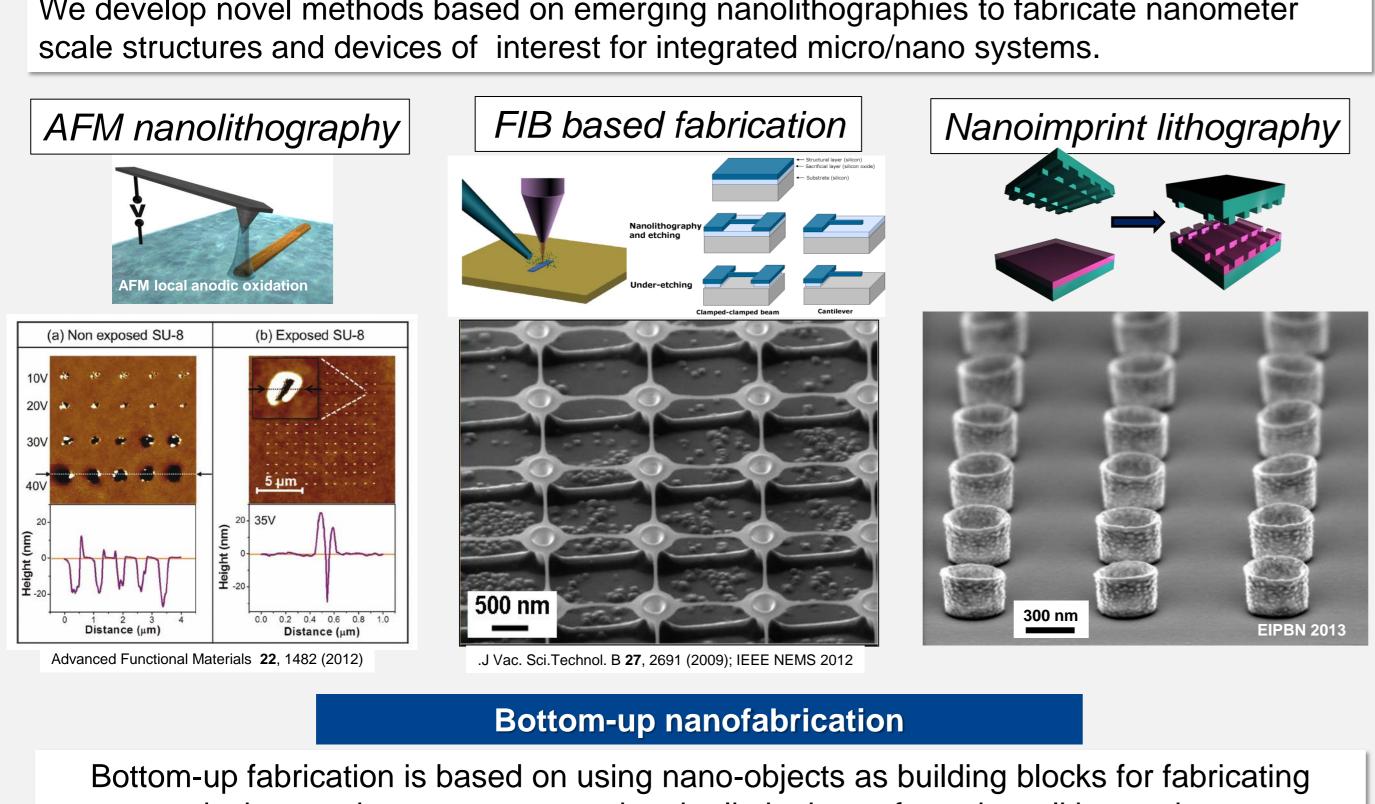
Research on nanomechanical and nanoelectronic structures and devices applicable in miniaturized integrated systems: nanofabrication technologies, advanced AFM methods and functional properties

NEMS Nanomechanical resonators Nanomechanical sensing Silicon nanowires present outstanding properties as mechanical resonators. We Mechanical structures and devices at nanometer scale present enhanced have developed processes to fabricate top-down and bottom-up nanowires, and performance as functional sensors. Transduction of the mechanical signal into methods to monolithically integrate nanomechanical resonators in CMOS circuits. electrical signal requires smart nanosystem designs. **NANOTECHNOLOGY** Silicon nanowire resonators (top-down and bottom-up) Piezoresistive cantilevers for biomolecular recognition Avidin-biotin bio-recognition event 500 nm Electrical detection of the frequency response of a bottom-up silicon nanowire mechanical resonato small Review of Scientific Instruments 83, 015002 (2012) Nanomechanical mass sensing with capacitive detection Applied Physics Letters 101, 243115 (2012) Measuring evaporation rate of femtoliter droplets $m+\delta m \rightarrow fres-\delta f$ CMOS integrated nanomechanical resonators Sustaining CMOS oscillator circui NEMS fabricated into CMOS by epeam litho + reactive ion etching Frequency (Hz) Journal of Physical Chemistry B, 111, 13020-13027 (2007); Nanotechnology 19, 305302 (2008) Lab on a Chip **11**, 2670 (2011) Nanotechnology 12, 100-104 (2001)

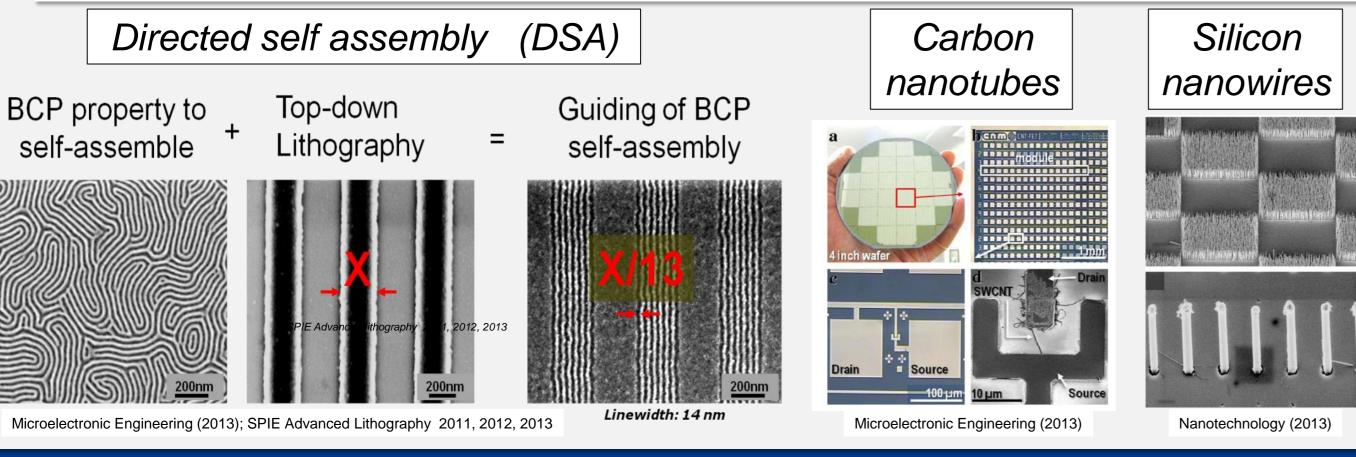


Top-down nanofabrication

We develop novel methods based on emerging nanolithographies to fabricate nanometer



devices and systems, surpassing the limitations of top-down lithography

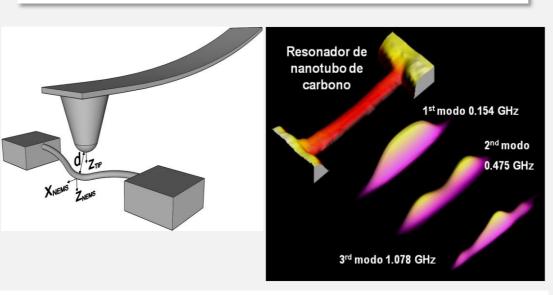


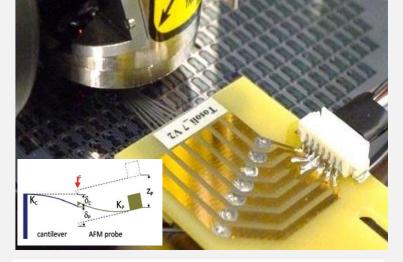
Atomic Force Microscopy

Advanced AFM characterization of nanometer scale devices

Multifrequency AFM to detect the eigen-modes of carbon nanotube mechanical resonators

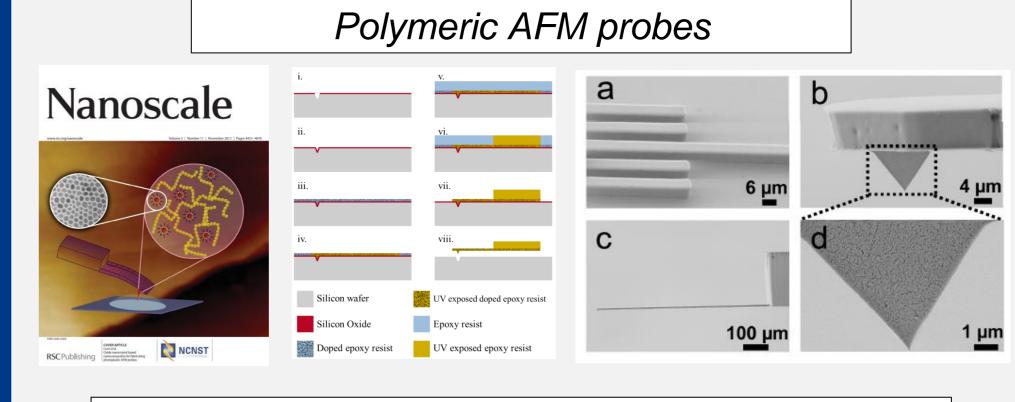
Electromechanical AFM characterization at wafer-scale level





Physical Review Letters 99, 085501 (2007); Physical Review B 85 035433 (2012)





AFM Cantilevers with (insulated) conducting tips

